Paper List

January―December, 2026

E2026-1(C)
Statistical Capacitance Measurement of Si Trench Capacitors Using 3D Stacked Array Test Circuit
IEEE 38th International Conference on Microelectronic Test Structures, (ICMTS2026), pp.7-11, March 23-26, (2026) , Matsue, Japan
Ryoya Nishimaki, Koga Saito, Takezo Mawaki, Rihito Kuroda

E2026-2(C)
A 72-dB SNR 1K-fps global shutter CMOS image sensor with dual pixel reset voltage and programmable gain amplifier
Society for Imaging Science and Technology,
Vol.38,ISS-288,pp.288-1-288-7,March, Electronic Imaging (2026), San Francisco, US
Kota Ogino, Takezo Mawaki, Rufuto Koba, Ken Miyauchi, Yushi Sakai, Rihito Kuroda
DOI: 10.2352/EI.2026.38.6.ISS-288

E2026-3(C)
A Global Shutter Proximity Capacitance CMOS Image Sensor for High-precision and High-speed Capacitance Imaging
Society for Imaging Science and Technology,
Vol.38,ISS-289,pp.289-1-289-6,March, Electronic Imaging (2026), San Francisco, US
Hiroto Ogura, Ukyo Kotake, Takezo Mawaki, Ken Miyauchi, Rihito Kuroda
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